

<b>Notice of References Cited</b>	Application/Control No. 10/587,546	Applicant(s)/Patent Under Reexamination BAI ET AL.	
	Examiner DANIEL C. MCCracken	Art Unit 1736	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
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#### FOREIGN PATENT DOCUMENTS

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#### NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Choi, et al., Controlled deposition of carbon nanotubes on a patterned substrate, Surface Science 2000; 462: 195-202
	V	Xu, et al., A method for fabricating large-area, patterned, carbon nanotube field emitters, Applied Physics Letters 1999; 74(17): 2549-2551
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.